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Application Information

Title Line One:: METHOD AND APPARATUS FOR ION Title Line Two:: ATTACHMENT MASS SPECTROMETRY

Title Line Three:: Title Line Four::

Total Drawing Sheets::

Docket Number:: 111522

Continuity Information

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Application One::

Filing Date:: Patent Number::

which is a:: Division of

>>Application Two::

Filing Date:: Patent Number::

Prior Foreign Applications

Foreign Application One::

JP 2000-401483 Filing Date:: December 28, 2000

Country::

Priority Claimed::

Foreign Application Two::

Filing Date:: Country::

Priority Claimed::

Foreign Application Three::

Filing Date:: Country::

Priority Claimed::

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